

**Effects of electrochemical reaction and surface morphology on electroactive
surface area of porous copper manufactured by Lost Carbonate Sintering**

Supplementary Information

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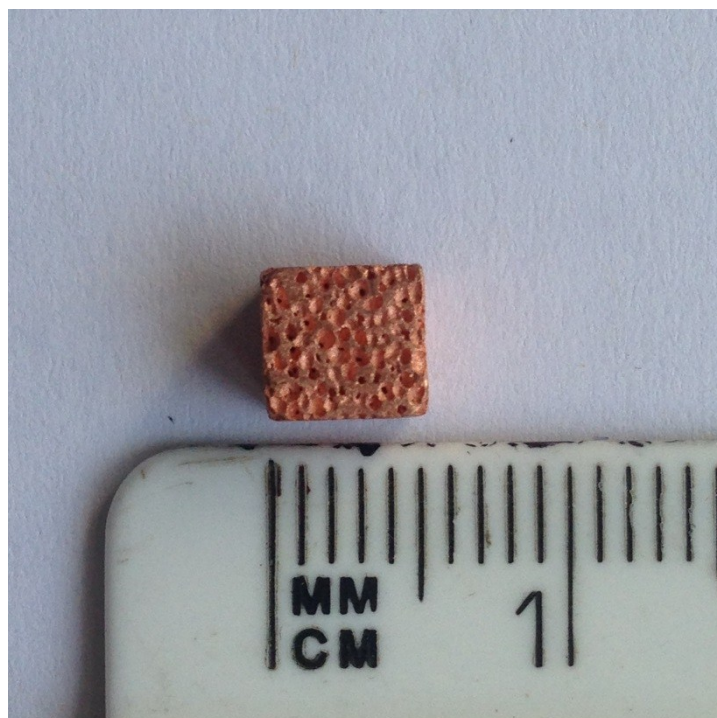


Fig. S1 The LCS porous Cu with a size of 5mm×5mm×4.8mm

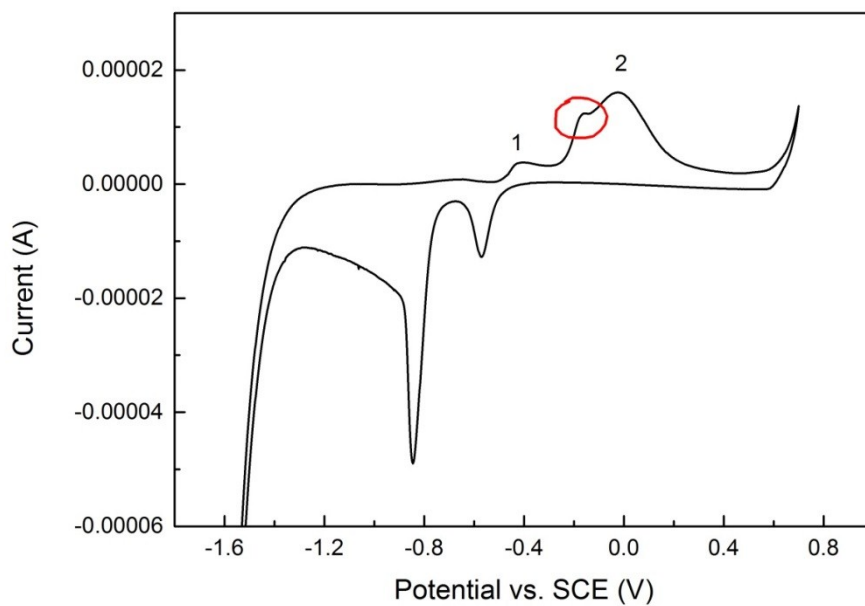
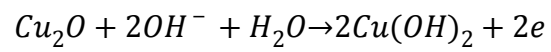


Fig. S2 The current-potential plot of a copper plate with a geometric surface area of 0.0543 cm² in 0.1 M KOH in the potential range of -1.6 to 0.7 V at a scan rate of 0.01 V/s

Another peak (marked in Fig. S2) occurs between peak 1 and peak 2 for copper plate. It is associated with the reaction below ^{1,2}:



This reaction is very sensitive to measurement conditions, e.g., scan rate. It is difficult to find this peak from the current-potential plots of the LCS Cu samples.

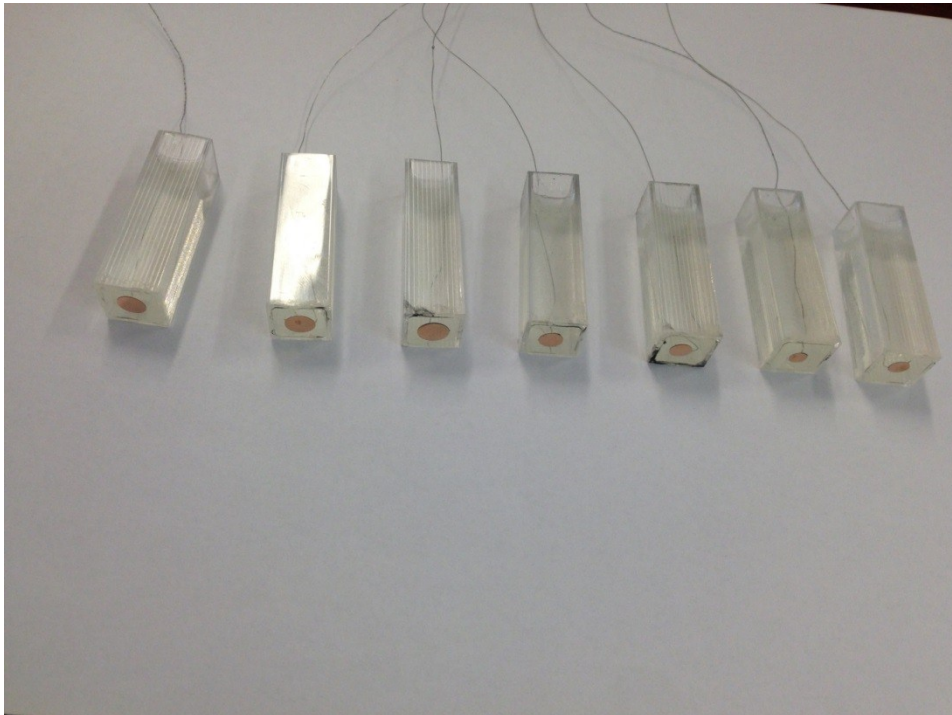


Fig. S3 Mirror polished copper plates with known geometric surface areas of 0.0543, 0.104
0.137, 0.171, 0.211, 0.252, 0.299 cm² (from right to left)

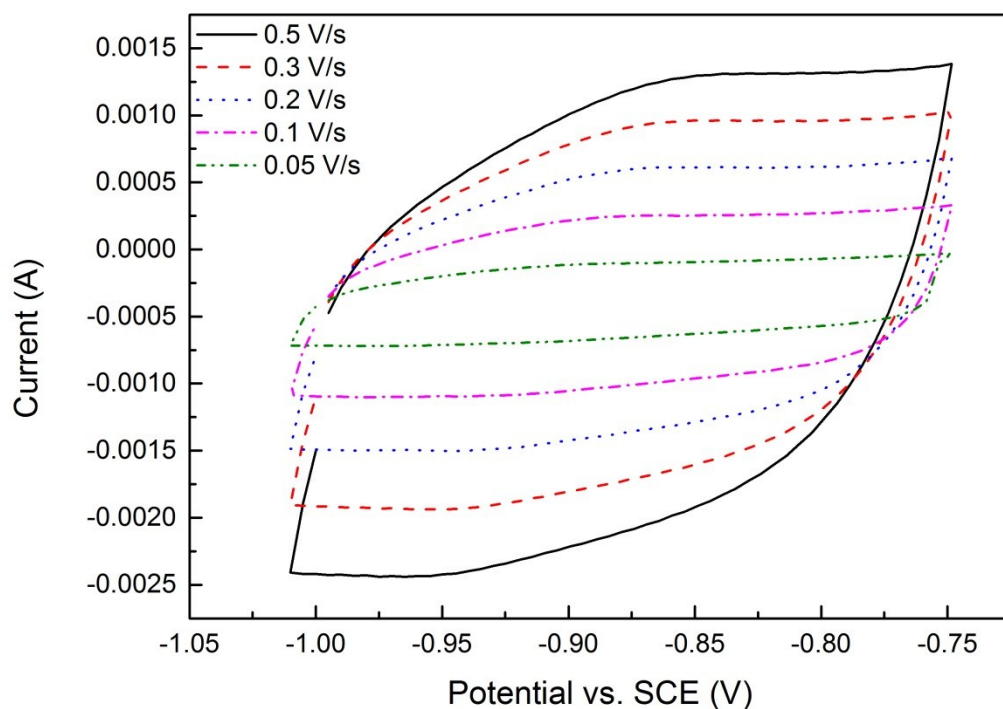


Fig. S4 Current-potential plots of the LCS Cu for real surface area measurement

Table S1 A_{Cu^+} (cm^{-1}) of the LCS Cu under different treatment conditions

| | | Treatment Conditions | | | | | | | | | | | | | | | |
|---------------------------|----------|----------------------|-------|-------|-------|------------------|-------|-------|-------|--------|-------|-------|-------|------------------|-------|-------|-------|
| | | 850 °C | | | | 850 °C & Etching | | | | 950 °C | | | | 950 °C & Etching | | | |
| | | < 20 | 20-45 | 45-75 | 75-90 | < 20 | 20-45 | 45-75 | 75-90 | < 20 | 20-45 | 45-75 | 75-90 | <20 | 20-45 | 45-75 | 75-90 |
| Particle size (μm) | Porosity | 534 | 742 | 841 | 707 | 435 | 632 | 659 | 519 | 219 | 222 | 303 | 204 | 142 | 177 | 226 | 189 |
| 0.50 | | 637 | 807 | 686 | 727 | 538 | 605 | 502 | 548 | 282 | 246 | 298 | 261 | 213 | 191 | 206 | 217 |
| 0.55 | | 795 | 787 | 772 | 739 | 520 | 625 | 579 | 550 | 257 | 270 | 308 | 258 | 197 | 214 | 229 | 188 |
| 0.60 | | 579 | 791 | 743 | 610 | 491 | 626 | 555 | 397 | 212 | 313 | 322 | 282 | 176 | 228 | 230 | 227 |
| 0.65 | | 601 | 835 | 718 | 677 | - | - | - | - | 253 | 345 | 368 | 284 | - | - | - | - |
| 0.70 | | 631 | 739 | 688 | 522 | - | - | - | - | 317 | 280 | 398 | 283 | - | - | - | - |
| 0.75 | | | | | | | | | | | | | | | | | |

Table S2 A_{OH^-} (cm^{-1}) of the LCS Cu under different treatment conditions

| Particle size (μm) Porosity | | Treatment Conditions | | | | | | | | | | | | | | | |
|--|-----|----------------------|-------|-------|-------|------------------|-------|-------|-------|--------|-------|-------|-------|------------------|-------|-------|-------|
| | | 850 °C | | | | 850 °C & Etching | | | | 950 °C | | | | 950 °C & Etching | | | |
| | | < 20 | 20-45 | 45-75 | 75-90 | < 20 | 20-45 | 45-75 | 75-90 | < 20 | 20-45 | 45-75 | 75-90 | <20 | 20-45 | 45-75 | 75-90 |
| 0.50 | 249 | 277 | 369 | 262 | 208 | 246 | 337 | 288 | 123 | 144 | 191 | 130 | 101 | 133 | 181 | 165 | |
| 0.55 | 270 | 296 | 371 | 300 | 248 | 238 | 353 | 272 | 186 | 166 | 189 | 176 | 166 | 162 | 192 | 189 | |
| 0.60 | 365 | 305 | 313 | 329 | 250 | 321 | 247 | 287 | 219 | 185 | 201 | 158 | 174 | 193 | 190 | 124 | |
| 0.65 | 265 | 324 | 310 | 278 | 257 | 303 | 249 | 253 | 158 | 189 | 214 | 203 | 161 | 200 | 202 | 183 | |
| 0.70 | 228 | 371 | 326 | 343 | - | - | - | - | 201 | 179 | 252 | 235 | - | - | - | - | |
| 0.75 | 299 | 332 | 337 | 275 | - | - | - | - | 222 | 218 | 266 | 242 | - | - | - | - | |

Table S3 A_r (cm^{-1}) of the LCS Cu under different treatment conditions

| Particle size (μm) Porosity | | Treatment Conditions | | | | | | | | | | | | | | | |
|--|------|----------------------|-------|-------|-------|------------------|-------|-------|-------|--------|-------|-------|-------|------------------|-------|-------|-------|
| | | 850 °C | | | | 850 °C & Etching | | | | 950 °C | | | | 950 °C & Etching | | | |
| | | < 20 | 20-45 | 45-75 | 75-90 | < 20 | 20-45 | 45-75 | 75-90 | < 20 | 20-45 | 45-75 | 75-90 | <20 | 20-45 | 45-75 | 75-90 |
| 0.5 | 1461 | 1720 | 1615 | 1624 | 1278 | 1683 | 1462 | 1466 | 677 | 929 | 959 | 890 | 677 | 851 | 1211 | 851 | |
| 0.55 | 1801 | 1878 | 1885 | 1724 | 1456 | 1678 | 1615 | 1380 | 965 | 1166 | 1104 | 1005 | 1166 | 925 | 1341 | 1005 | |
| 0.6 | 1902 | 1870 | 1808 | 1689 | 1585 | 1675 | 1577 | 1375 | 1274 | 1006 | 1250 | 1006 | 1234 | 1200 | 1074 | 851 | |
| 0.65 | 1771 | 1895 | 1760 | 1545 | 1456 | 1727 | 1440 | 1120 | 1074 | 1144 | 1314 | 1155 | 959 | 1104 | 1115 | 1035 | |
| 0.7 | 1848 | 2015 | 1732 | 1729 | - | - | - | - | 1138 | 1341 | 1461 | 1253 | - | - | - | - | |
| 0.75 | 1664 | 1909 | 1867 | 1711 | - | - | - | - | 1407 | 1353 | 1575 | 1340 | - | - | - | - | |

References

1. N. Hampson, J. Lee and K. Macdonald, *Journal of Electroanalytical Chemistry and Interfacial Electrochemistry*, 1972, **34**, 91-99.
2. J. Ambrose, R. Barradas and D. Shoesmith, *Journal of Electroanalytical Chemistry and Interfacial Electrochemistry*, 1973, **47**, 47-64.